

ABSTRACT

A substrate and workpiece carrier for holding the substrate, for example, a thin film substrate, during substrate processing, having a holder that holds and positions the substrate. The workpiece carrier includes a base element for holding the substrate, the base element provided on a handling element, and process-dependent cover elements may be assigned to the base element on a side opposite the handling element. In addition, the substrate and the workpiece carrier each have at least one complementary positioning element which is used to secure the substrate in a relative spatial position (positioning unit).